

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Peter CHOI

Title: PLASMA SOURCE OF DIRECTED
BEAMS AND APPLICATION THEREOF
TO MICROLITHOGRAPHY

Based Upon: PCT/FR2004/002656

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FIRST PRELIMINARY AMENDMENT**Mail Stop PCT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

Please amend the subject U.S. Patent Application as follows to place this U.S. Patent Application in better condition for examination.

In the claims, substitute the following Claims 1-30 (Currently Amended) for the pending Claims 1-30 (Original).